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**INFORMATION DISCLOSURE STATEMENT
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Applicant: Ralph KURT ET AL.

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Examiner: Daborah Chako Davis

Group Art Unit: 1756

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
DCD	AR	2001/0026354	A1	10/04/2001	Aoki	
DCD	BR	6,025,115	A	02/15/2000	Komatsu et al.	
	CR					
	DR					
	ER					
	FR					
	GR					
	HR					
	IR					
	JR					

FOREIGN PATENT DOCUMENTS

		Document Number		Date MM/YYYY	Country	Inventor Name		Abstract		Readily Available	
								Enclosed	No	Enclose	No
DCD	KR	0 227 839	A1	07/08/1987	European Patent Office	Yamazaki et al.				X	
DCD	LR	1 312 983	A2	05/21/2003	European Patent Office	Van Schaik et al.				X	
DCD	MR	03/075098	A2	09/12/2003	PCT	Wedowski et al.					X
	NR										
	OR										
	PR										
	QR										
	RR										
	SR										
	TR										

OTHER (Including in this order: Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

DCD	UR	BLOOMSTEIN T.M. et al.; "Laser cleaning of optical elements in 157-nm lithography", proceedings of SPIE, Vol. 4000, pp. 1537-1545 (July 31, 2000), XP-002321000				X	
DCD	VR	European Search Report issued in EP Application No. 03256103.7 dated December 2, 2005				X	
	WR						
	XR						
	YR						
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